

Dutch Metrology Institute

IMPRESS II – WP3: Flow Uncertainty and Impact on Annualised Mass Emissions

Overview of the work package VSL, NPL, ISSI, CMI, TU Delft, CNR Marcel Workamp 11 January 2021





/SL WP3: Relevant standards

- This work package deals with flow rate measurement of emissions, primarily focused on relatively narrow stacks.
- Reference method for emission flow measurement:
 - EN ISO 16911-1 and EN ISO 16911-2 Stationary source emissions Manual and automatic determination of *velocity* and *volume flow rate* in ducts
 - Part 1: Manual reference method
 - Part 2: Automated measuring systems (refers to Part 1 for calibration)
 - EN 15259 Air quality. Measurement of stationary source emissions. Requirements for measurement sections and sites and for the measurement objective, plan and report
 - Sets requirements for the sampling plane and sampling points (tangential method required)
- How well does the reference method perform in narrow stacks?



VSL WP3: ISO 16911-1

- Provides a method for the determination of gas velocity and volume flow rate within an emission duct
- Describes a method to determine the velocity profile of the gas flow across a measurement plane in the duct
- Gives a method to determine the total volume flow rate at a measurement plane in the duct based on a grid of point velocity measurements (typically done with Pitot tubes)
- Described alternative methods: tracer dilution, tracer transit time, and by calculation from energy consumption

The volume flow rate, q_V , is determined by multiplying the average velocity by the area of the measurement plane (i.e. the internal area of the duct at the measurement plane).

$$q_V = \overline{v}_p A$$

(1)

where

- \overline{v}_{p} is the average of the point velocity measurements;
- A is the area of the measurement plane.



VSL WP3: EN 15259 requirements

- b) measurement plane shall be situated in a section of the waste gas duct (stack etc.) where homogenous flow conditions and concentrations can be expected;
 - NOTE 4 The requirement for homogeneous flow conditions is generally fulfilled if the measurement plane is
 - as far downstream and upstream from any disturbance, which could produce a change in direction of flow (e.g. disturbances can be caused by bends, fans or partially closed dampers),
 - in a section of a duct with at least five hydraulic diameters of straight duct upstream of the sampling plane and two hydraulic diameters downstream (five hydraulic diameters from the top of a stack; see A.2) and
 - in a section of a duct with constant shape and cross-sectional area.







VSL WP3: EN 15259 requirements

c) measurements at all the sampling points defined in 8.2 and Annex D shall prove that the gas stream at the measurement plane meets the following requirements:

1)	ar	Table 2 — Minimum number of sampling points for circular ducts				
NOTE		Range of	Range of ducts	Minimum number of	Minimum number of	
2)	nc	areas	diameters	(diameters)	sampling points per plane	
3)	mi pr	m²	m			
4)	ra	< 0,1	< 0,35	-	1 ^a	
	-	0,1 to 1,0	0,35 to 1,1	2	4	
of st	tra	1,1 to 2,0	>1,1 to 1,6	2	8	
diam	net	> 2,0	> 1,6	2	at least 12 and 4 per m ^{2 b}	



Figure D.2 — Sampling point positions in circular ducts – Tangential method (showing positions for ducts over 2 m diameter)

^a Using only one sampling point can give rise to errors greater than those specified in this European Standard.

^b For large ducts, 20 sampling points are generally sufficient.



Investigation of flow monitoring technologies and the use of multiple sensors in stacks

Traceable

uncertainties of

propagated for

under real field

conditions

annualised mass

emission reporting

flow measurements

Impact of wall effects and sensor obstruction in pipes and ducts

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To determine the uncertainties and provide traceability of mass emission measurements related to flow calibrations carried out in field conditions

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WP 3: Flow uncertainty and impact on annualised mass emissions

- Task 3.1: Traceable uncertainties of flow measurements propagated for annualised mass emission reporting under real field conditions
 - Evaluation of uncertainty sources and modelling by NPL
- Task 3.2: Impact of wall effects and sensor obstruction in pipes and ducts
 - Experiments by VSL
 - Simulations by TU Delft
- Task 3.3: Investigation of flow monitoring technologies and the use of multiple sensors in stacks
 - Effects of flow disturbances
 - Experiments by VSL
 - Simulations by CMI
 - Using different flow monitoring techniques
 - Measurements/comparisons by CNR & ISSI

Task 3.2: Impact of wall effects and sensor obstruction in pipes and ducts

- Experiments by VSL:
 - Sensor obstruction effects:
 - Part of the duct is blocked by the pitot tube, what is the uncertainty and error associated to that?
 - Calculations based on experimental parameters
 - Measurements to determine wall effects
 - Using S- and L-type pitot tubes at various distance from the wall in "ideal" conditions
 - Calculation of known corrections for L-type pitot tubes
 - Comparing experiments to theoretical prediction of the flow profile
- Simulations by TU Delft:
 - Numerical simulations with OpenFOAM to obtain flow profiles at relevant Reynolds numbers
 - Predictions for S-Pitot measurements









L-Pitot



Both cases >10 hydraulic diameters of straight duct upstream of the Pitot tube

VSL Task 3.2: Experimental results

- Wall effects:
 - S-Pitot tubes have a tendency to underreport near the wall, but above 5 cm distance from the wall (required by standards), there is no notable difference.
 - Known corrections for L-Pitot tubes are small and not always easily calculated (see e.g. [1,2])
 - 2% correction for the case where the L-pitot was laying flat on the duct wall
 - Negligible when more than a cm away from the wall



[1] F. A. MacMillan, "Experiments on Pitot-tubes in shear flow", 1956[2] B. J. McKeon et al., "Pitot probe corrections in fully developed turbulent pipe flow", 2003

VSL Task 3.2: Experimental results

- Sensor obstruction effects:
 - Corrections can be made for S-Pitot tubes, correction factor:
 - $\frac{A A_{pitot}}{A}$
 - Effects are typically small compared to the total measurement uncertainty

Bulk velocity	Uncorrected velocity	Corrected velocity
\overline{u}_{bulk} [m/s]	$ar{u}_z$ [m/s]	\overline{u}'_{z} [m/s]
3.14	3.87±6.4%	3.80±7.6%
4.75	5.80±4.3%	5.69±5.8%
7.56	8.97±2.4%	8.80±4.7%
9.67	11.42±2.2%	11.20±4.5%





SL Task 3.2: Numerical results

- Flow around S-Pitot tube successfully simulated
- Also here it is found that S-Pitot tubes have a tendency to underreport the velocity





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- WP3 successfully completed
- 1 MSc thesis delivered

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3 papers were written of which 2 are already published (open access!):

Technical Paper	Open Access Article	
Narrow stack emissions: Errors in flow rate measurement due to disturbances and swirl Stanislav Knotek Image: Distance in the second state in the	Spectroscopic Techniques versus Pitot Tube for the Measurement of Flow Velocity in Narrow Ducts by O Francesco D'Amato 1 2 , O Silvia Viciani 1,* 2 , O Alessio Montori 1 , O Marco Barucci 1 Carmen Morreale 2 , O Silvia Bertagna 2 and O Gabriele Migliavacca 2 1 OND NO. Area OND Via Mederare del Direc 40, 50040 Parte Disconting Italy	
🖹 Full Article 📧 Figures & data 🛛 References 🕀 Supplemental 💕 Citations 🔟 Metrics © Licensing 🖶 Reprints & Permissions 🗋 PDF	 ² Innovhub Stazioni Sperimentali per l'Industria srl, Via G. Galilei 1, 20097 San Donato Milanese, Italy [*] Author to whom correspondence should be addressed. 	
•	Sensors 2020, 20(24), 7349; https://doi.org/10.3390/s20247349	

Using both experiments and models, much insight was gained into the uncertainties of emission flow measurement, particularly for narrow stacks.